

ABSTRACT

The present invention intends to provide a baking apparatus for PDP capable of realizing an improvement in productivity while minimizing an increase in a factory space. In a baking furnace 2 for performing heat treatment while conveying substrates 4, conveying means 6 of multiple stages for conveying substrates are provided. The conveying means 6 adjacent in an up and down direction are divided with heat insulating partitions 7 provided between them so as to form a multi-stage furnace, and heating means 9 are provided appropriately to the heat insulating partitions 7. In each furnace of the multi-stage furnace, a heating area, a keeping area and a cooling area are formed in order in the traveling direction of the conveying means, whereby baking of plasma display panels is performed in multiple stages.